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Roland Geyl

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Contents

vii	Authors
ix	Conference Committee

OPTICAL SYSTEMS

- 10692 02 **Optical window detachment using a 3-axis hotwire system (Invited Paper)** [10692-1]
- 10692 03 **Automated centration measurement and quality inspection of aspheric lenses** [10692-2]
- 10692 04 **Mechanical strength of optical glasses** [10692-3]

MICROOPTICS

- 10692 06 **Evaluation of lenslet fabrication technologies for micro-optical array projectors** [10692-5]
- 10692 07 **Improved calibration of vertical scanning optical profilometers for spherical profiles measurements** [10692-6]
- 10692 08 **Holographic prism based on photo-thermo-refractive glass: new facilities for metrological application** [10692-7]

SPACE OPTICS

- 10692 09 **World Space Observatory - Ultraviolet Mission: instrumentation update and status 2018 (Invited Paper)** [10692-8]
- 10692 0A **Freeform optics design and manufacturing for MicroCarb** [10692-9]
- 10692 0B **EUCLID: design, analysis, fabrication, and test of a 1.3m collimator for the on-ground characterization of the EUCLID Payload Module** [10692-10]
- 10692 0C **Additive manufacturing of metal mirrors for TMA telescope** [10692-11]
- 10692 0D **The MTG-SSA multi-purpose and multi-wavelength infrared test bench** [10692-12]

GRATINGS AND FUNCTIONAL SURFACES

- 10692 0E **Simulation of defect-induced scattering in multilayer coatings (Invited Paper)** [10692-13]
- 10692 0G **Scattering from reflective diffraction gratings: the challenges of measurement and verification (Invited Paper)** [10692-15]
- 10692 0H **Optical gratings with low wavefront aberrations and low straylight for enhanced spectroscopical applications** [10692-16]
- 10692 0I **Diffuse scattering of lamellar optical gratings due to line edge roughness** [10692-17]

FREEFORMS

- 10692 0K **Novel applications based on freeform technologies (Invited Paper)** [10692-19]
- 10692 0L **Larger format freeform fabrication and metrology** [10692-20]
- 10692 0M **Improved ion beam tools for ultra-precision figure correction of curved aluminium mirror surfaces** [10692-21]
- 10692 0N **Advanced techniques for robotic polishing of aluminum mirrors** [10692-22]
- 10692 0O **Shape measurement of freeform optics (Invited Paper)** [10692-23]
- 10692 0P **Advanced optical freeform substrates fabricated by ceramic 3D printing and controlled by deflectometry** [10692-24]
- 10692 0Q **Fabrication and measurement of freeform mirror for head-up display system** [10692-25]

OPTICAL FABRICATION

- 10692 0X **Pushing SiC polishing technology for advanced applications** [10692-30]
- 10692 0Y **Three wagons method to analyze ductile mode grinding processes (Invited Paper)** [10692-33]
- 10692 0Z **Ductile grinding of tungsten carbide applying standard CNC machines: a process analysis** [10692-34]
- 10692 10 **Process control in ductile mode machining of tungsten carbide (Invited Paper)** [10692-31]
- 10692 11 **Load controlled process window analysis of feed controlled CNC grinding** [10692-32]

METROLOGY I

- 10692 16 **Obtaining the topography of human corneas with the null-screen testing method** [10692-37]
- 10692 17 **Optoelectronic system modulation transfer function measurement based on the method of summation over different frequencies harmonic functions** [10692-40]

METROLOGY II

- 10692 19 **Characterization of gratings for space applications** [10692-38]

POSTER SESSION

- 10692 1C **Modeling of luminous stream in photovoltaic systems** [10692-43]
- 10692 1D **The study of sub-surface damage of fused silica after ultrasonic assisted grinding process** [10692-44]
- 10692 1E **Analysis of method of determination of refractive index and Abbe number of lens** [10692-45]
- 10692 1F **Effect of visibility of the fringes on the tilt measurement using a cyclic interferometer and polarization phase shifting** [10692-46]
- 10692 1G **The matters of producing optical elements for educational purposes** [10692-47]
- 10692 1H **Hyperspectrometer based on curved prism fabrication for space application** [10692-48]
- 10692 1J **Dynamic null-screens: a proposal for characterizing the PTSC with adaptive patterns** [10692-50]
- 10692 1K **Analysis of industrial production environments and derivation of a novel channel model towards optical wireless communication** [10692-51]

Authors

Numbers in the index correspond to the last two digits of the seven-digit citation identifier (CID) article numbering system used in Proceedings of SPIE. The first five digits reflect the volume number. Base 36 numbering is employed for the last two digits and indicates the order of articles within the volume. Numbers start with 00, 01, 02, 03, 04, 05, 06, 07, 08, 09, 0A, 0B...0Z, followed by 10-1Z, 20-2Z, etc.

- | | |
|-----------------------------------|--------------------------------|
| Achour, Sakina, 19 | Gloesener, Pierre, 0B |
| Aguirre Aguirre, Daniel, 16 | Gorokhovsky, K. S., 08 |
| Aguirre-Caro, Jesús Alberto, 1J | Granovskii, V. A., 08 |
| Angervaks, A. E., 08 | Hahne, F., 03 |
| Armengol-Cruz, Victor Emanuel, 16 | Haret, Laurent-Daniel, 0D |
| Arnold, Thomas, 0M | Hartmann, Peter, 04 |
| Banasch, Michael, 0I | Hartung, Johannes, 0C, 0K |
| Barré, Frédéric, 0D | Haumont, Thierry, 0D |
| Bauer, Jens, 0M | Heidler, Nils, 0C |
| Béguelin, Jeremy, 07 | Heusinger, Martin, 0I |
| Beier, Matthias, 0K | Hilpert, Enrico, 0C |
| Belyaeva, Alina, 1G | Houllier, Thomas, 0P |
| Bernal, A., 1F | Huang, Chien-Yao, 1D |
| Berruée, Romain, 0D | Hugues, Vincent, 0D |
| Beutler, Andreas, 0O | Ilinski, Aleksandr V., 17 |
| Blalock, Todd, 0L | Ivanov, S. A., 08 |
| Brunelle, Matthew, 0L | Jasperneite, Jürgen, 1K |
| Burkhardt, Matthias, 0H | Jiao, Hongfei, 0E |
| Butova, Daria, 1G | Jing, Juanjuan, 1H |
| Camargo-Fierro, Christian, 16 | Joenathan, C., 1F |
| Campos-García, Manuel, 16, 1J | Joseph, S., 02 |
| Chang, Keng-Shou, 1D | Kalies, Alexander, 0H |
| Chaussat, G., 0X | Khaled, Abou-El-Hossein, 0Q |
| Chen, Fong-Zhi, 0Q | Kleinle, Sylke, 06 |
| Cheng, Xinbin, 0E | Klocke, F., 0Z, 10 |
| Cheng, Yuan-Chieh, 0Q | Koch, Felix, 0H |
| Chou, Hsiao-Yu, 0Q | Koszo, Manon, 0D |
| Cloutrier, Christophe, 0D | Kozhina, Anastasia, 1G |
| Dambon, Olaf, 0Y, 0Z, 10 | Kroneberger, Monika, 0G |
| Damm, Christoph, 0C | Kuo, Ching-Hsiang, 1D |
| Dannberg, Peter, 06 | Kuperman-Le Bihan, Quentin, 19 |
| DeGroote Nelson, Jessica, 0L | Langehanenberg, P., 03 |
| Díaz-Uribe, José Rufino, 1J | Langenbach, Eckhard, 0Y, 10 |
| Diehl, Torsten, 0H | Lehr, Dennis, 0H |
| Doan, Van Bak, 08 | Leitel, Robert, 06 |
| Doetz, Marius, 0Y, 0Z, 10 | Lemagne, Fabien, 0B |
| Erdmann, Lars H., 0H | Lépine, Thierry, 0P |
| Espinosa-Nava, Ulises, 1J | Leplan, H., 0A, 0X |
| Etcheto, Pierre, 19 | Levy, A., 02 |
| Faehnle, Oliver, 0Y, 0Z, 10, 11 | Li, Hongyu, 0N |
| Feng, Lei, 1H | Li, Tony, 0N |
| Ferrallì, Ian, 0L | Li, Yacan, 1H |
| Fischer, Stephanie, 06 | Lopez, S., 0A |
| Flatt, Holger, 1K | Lousberg, Grégory P., 0B |
| Flebus, Carlo, 0B | Lyamets, Dmitry, 1G |
| Flügel-Paul, Thomas, 0I | Lynch, Timothy, 0L |
| Ganesan, A. R., 1F | Maltseva, Nadezhda K., 17 |
| Gatto, Alexandre, 0H | Mezger, Andreas, 0G |
| Geyl, R., 0A, 0X | Michaelis, Dirk, 0I |

- Miks, Antonin, 1E
 Moeller, Tobias, 0H
 Monaci, Denis, 0D
 Monamy, Virgile, 0B
 Moreau, Fabien, 0D
 Nikonorov, N. V., 08
 Noell, Wilfried, 07
 Novak, Jiri, 1E
 Novak, Pavel, 1E
 Nurpeisova, Diana, 1G
 Okun, R. A., 08
 Orekhova, Maria K., 1G
 Peña-Conzuelo, Andrés, 1J
 Peng , Wei-Jei, 0Q
 Perezyabov, Oleg A., 17
 Pesch, Alexander, 0H
 Peschel, Thomas, 0C
 Pietag, Fred, 0M
 Pirnay, Olivier, 0B
 Plachta, Kamil, 1C
 Plainchamp, Bertrand, 0D
 Pokorny, Petr, 1E
 Pretheesh Kumar, V. C., 1F
 Rascher, R., 0Z, 11
 Reynolds, Christina, 0N
 Rieth, Katja, 0B
 Riguet, Francois, 0A, 0D
 Risse, Stefan, 0C, 0K
 Rodolfo, Jacques, 0D
 Rousselet, Nicolas, 0P
 Ruch, E., 0A
 Ryskin, A. I., 08
 Sachkov, Mikhail, 09
 Scharf, Toralf, 07
 Schneider, Daniel, 1K
 Schreiber, Peter, 06
 Schröder, Sven, 0E
 Shinman-Avraham, A. E., 02
 Shu, Shyu-Cheng, 1D
 Smejkal, Filip, 1E
 Smejkal, Michal, 1E
 Stübbe, Oliver, 1K
 Surrel, Yves, 0P
 Tolstoba, Nadezhda, 1G
 Triebel, Peter, 0H
 Trost, Marcus, 0E
 Ulitschka, Melanie, 0M
 Voelkel, Reinhard, 07
 Vogt, C., 0Z, 11
 Volatier, Jean-Baptiste, 0G
 von Lukowicz, Henrik, 0C
 Wächter, Christoph, 06
 Walker, David, 0N
 Wang, Zhanshan, 0E
 Weber, Y. B., 02
 Wei, Lidong, 1H
 Yadlovker, D., 02
 Yang, Lei, 1H
 Yu, Guoyu, 0N
 Yu, Zong-Ru, 1D

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- 7 Optical Fabrication
Roland Geyl, Safran Reosc (France)
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- 9 Metrology II
Christof Pruss, Institut für Technische Optik (Germany)